

# Real-time POU Monitor of CMP Slurry

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# In-Situ Real Time Monitoring of Slurry



Slurry from Delivery System

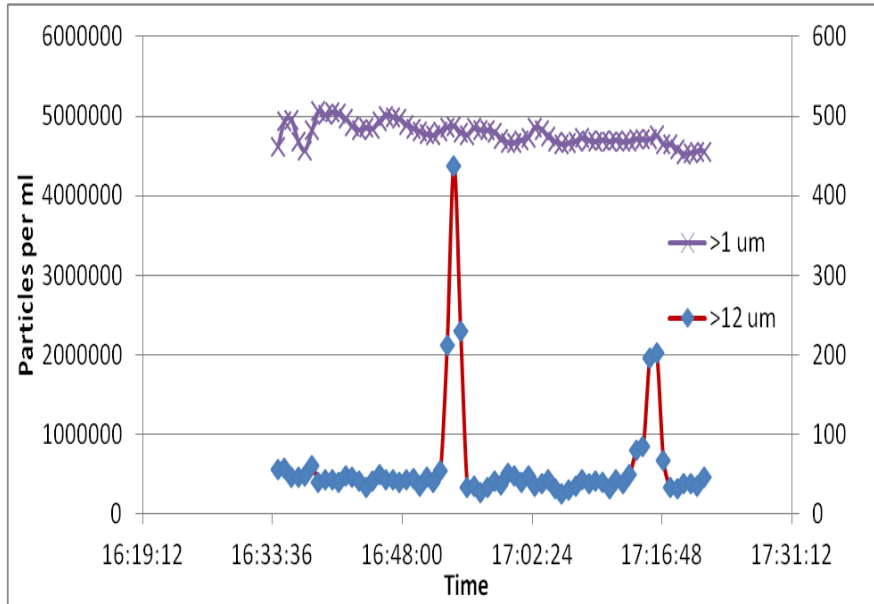


LPC Measured in Real Time

Slurry Dispensed on Platen

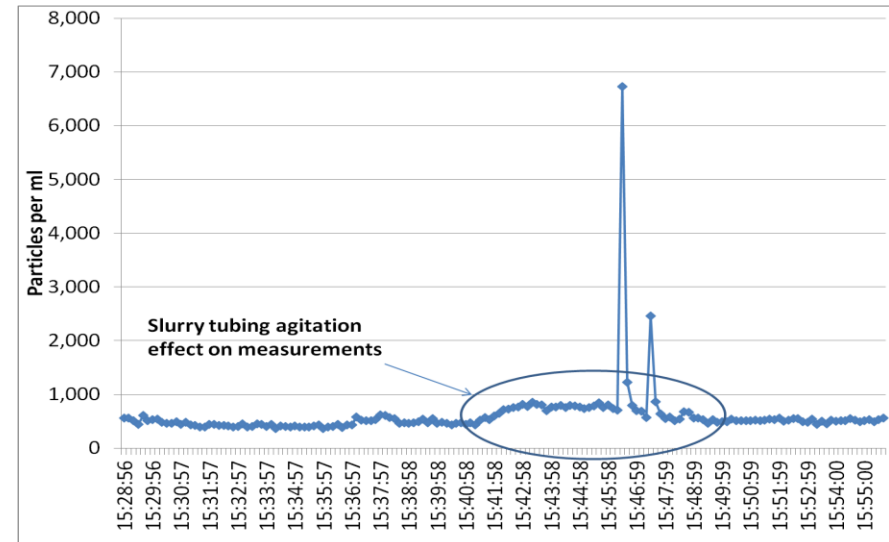


# Data and Observations

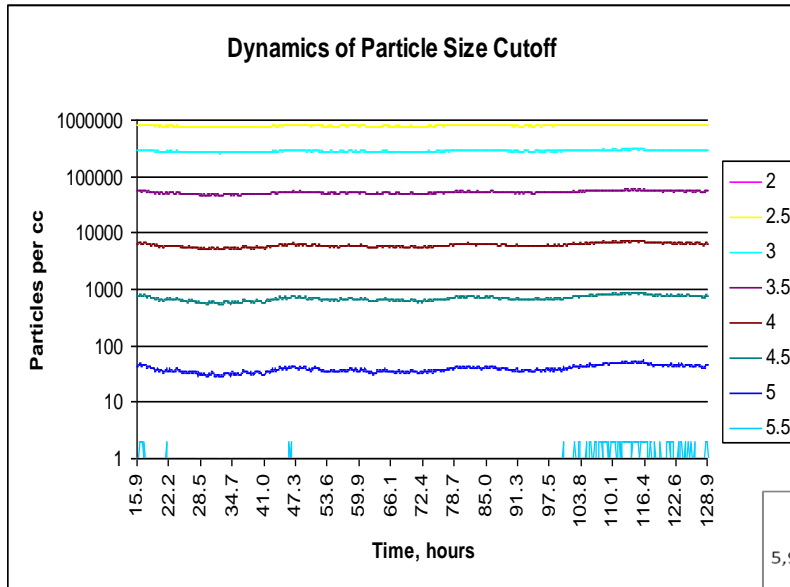


Short Duration LPC total  
Count excursions

Short Duration LPC excursions  
By particle size



# Data and Observations ( cont'd)



LPC detection

LPC and defects  
On wafer

